Amendments to the claims:

14. (currently amended) An apparatus for coating at least one of the front and rear facets of semiconductor laser diodes, ~~(lasers)~~, with an anti-reflection layer of minimal rest reflectivity, said apparatus including means for monitoring, in-situ, at least one of laser parameters of each laser, including laser light emitted from at least one of the front and rear facets of each laser, the electric voltage at a p-n junction of the laser, the quantum efficiency of the laser light emitted from at least one of the front and rear facet of the laser, and the threshold current of the laser, said apparatus comprising a receiver for containing lasers to be coated, a coating source disposed in said receiver, a support structure for supporting said lasers to be coated such that said lasers are supported with their facets all at essentially the same distance from said coating source, and for each laser ~~a~~ an individual shutter supported in said receiver so as to be movable selectively in front of said lasers to protect them from further coating when the laser parameters indicate that an optimum coating stage has been reached for a particular laser.

15. (previously amended) An apparatus according to claim 14, wherein said lasers are supported on a support structure forming a magazine by which they can be moved into, and out of, said receiver.

16. (original) An apparatus according to claim 14, wherein said lasers are arranged in a circle around said coating source.

17. (previously amended) An apparatus according to claim 14, wherein said lasers are arranged linearly along lines disposed at opposite sides equidistantly from a center line.

18. (previously amended) An apparatus according to claim 14, wherein a control unit is provided which monitors the laser parameter of said lasers disposed in said receiver for the coating thickness of their facets while each laser is electrically operated.

19. (original) An apparatus according to claim 18, wherein said control unit includes at least one of a laser control, a shutter control, a layer thickness and a vacuum control arrangement.

20. (amended) An apparatus according to claim 19, wherein said control unit is in communication with said coating source, said laser support and said shutter ~~support structure~~ by at least one of electrical and optical conduits.